

IN THE U.S. PATENT AND TRADEMARK OFFICE

in re application of:

Hidemitsu AOKI et al.

Confirmation No. 6696

Serial No. 09/715,000

GROUP 2825

Filed November 20, 2000 Examiner Chuong A. Luu

IMPROVED SEMICONDUCTOR WAFER SURFACE AND METHOD OF TREATING A SEMICONDUCTOR WAFER SURFACE

AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 March 11, 2004

Sir:

In response to the Official Action mailed December 2, 2003, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.